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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Alan P. Sheng et al.
Serial No: 10/730,863
Confirmation No: 3529
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For: SYSTEM AND METHOD FOR MULTI-WAFER SCANNING
IN ION IMPLANTERS
Examiner: Jack I. Berman
Art Unit: 2881

CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)

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Mark Superko

Commissioner for Patents
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Alexandria, VA 22313-1450

Sir:

AMENDMENT

In response to the Office Action mailed February 23, 2005, please amend the above-identified application as follows.